# Measurement of Electron Density Fluctuations using Microwave Reflectometer in Heliotron J

ヘリオトロンJにおけるマイクロ波反射計を用いた電子密度揺動計測

<u>Koji Mizuno</u><sup>1)</sup>, Kazunobu Nagasaki<sup>2)</sup>, Kiyofumi Mukai<sup>1)</sup>, Yuichi Nakamura<sup>1)</sup>, Takeshi Fukuda<sup>3)</sup>, Teresa Estrada<sup>4)</sup>, Shinsuke Ohshima<sup>5)</sup>, Tohru Mizuuchi<sup>2)</sup>, Takashi Minami<sup>2)</sup>, Hiroyuki Okada<sup>2)</sup>, Kai Masuda<sup>2)</sup>, Shinji Kobayashi<sup>2)</sup>, Satoshi Yamamoto<sup>2)</sup>, Hyunyong Lee<sup>1)</sup>, Linge Zang<sup>1)</sup>, Shohei Arai<sup>1)</sup>, Tasuku Kagawa<sup>1)</sup>, Takayuki Minami<sup>1)</sup>, Hiroaki Yashiro<sup>1)</sup>, Hiroto Watada<sup>1)</sup>, Yoshinobu Wada<sup>1)</sup>, Yuji Nakamura<sup>1)</sup>, Kiyoshi Hanatani<sup>2)</sup>, Shigeru Konoshima<sup>2)</sup>, Fumimichi Sano<sup>2)</sup> <u>水野浩志</u><sup>1)</sup>, 長崎百伸<sup>2)</sup>, 向井清史<sup>1)</sup>, 中村雄一<sup>1)</sup>, 福田武司<sup>3)</sup>, T. Estrada<sup>4)</sup>, 大島慎介<sup>5)</sup>, 水内亨<sup>2)</sup>, 南貴司<sup>2)</sup>, 岡田浩之<sup>2)</sup>, 增田開<sup>2)</sup>, 小林進二<sup>2)</sup>, 山本聡<sup>2)</sup>, H.Y. Lee<sup>1)</sup>, L. Zang<sup>1)</sup>, 荒井翔平<sup>1)</sup>, 香川輔<sup>1)</sup>, 南貴之<sup>1)</sup>, 八代浩彰<sup>1)</sup>, 和多田泰士<sup>1)</sup>, 和田善信<sup>1)</sup>, 中村祐司<sup>1)</sup>, 花谷清<sup>2)</sup>, 木島滋<sup>2)</sup>, 佐野史道<sup>2)</sup>

 Graduate School of Energy Science, Kyoto University, Gokasho, Uji, Kyoto, Japan 京都大学大学院エネルギー科学研究科 〒611-0011 京都府宇治市五ヶ庄
Institute of Advanced Energy, Gokasho, Uji, Kyoto University, Gokasho, Uji, Kyoto, Japan 京都大学エネルギー理工学研究所 〒611-0011 京都府宇治市五ヶ庄
Center for Atomic and Molecular Technologies, Osaka University, 2-1, Yamadaoka, Suita, Osaka, Japan 大阪大学原子分子イオン制御理工学センター 〒565-0871 大阪府吹田市山田丘 2-1 4) Laboratorio Nacional de Fusión, EURATOM-CIEMAT, Spain
Pioneering Research Unit for Next Generation, Kyoto University, Gokasho, Uji, Kyoto, Japan 京都大学次世代開拓ユニット 〒611-0011 京都府宇治市五ヶ庄

A microwave reflectometer for measurement of electron density fluctuations is developed in Heliotron J. The injection frequency of microwave ranges from 24.75 to 42 GHz corresponding to the O-mode cut-off density from 0.8 to  $2.2 \times 10^{19}$  m<sup>-3</sup>. A characteristic test with a vibrating reflector shows that the output signal from the emitting horn has intensity from -10 to -5 dBm over the frequency range and that the reflectometer can measure fluctuations corresponding to frequency given to the vibrating reflector.

# 1. Introduction

It is necessary to understand the mechanism of anomalous transport to improve plasma confinement. It is considered that anomalous transport comes from fluctuations of magnetic field, electric field, plasma density, and temperature out of various instability of plasma. Therefore, it is important to measure these parameters.

Measurement of density fluctuations with and beam Langmuir probes а emission spectroscopy has been developed and performed in Heliotron J. However, they can apply only to edge plasma or NBI plasma. Microwave reflectometer has a capability of measuring fluctuations over the confinement region for ECH and/or NBI plasmas by choosing injection frequency. In this research, developing we have been a microwave reflectometer system to measure electron density fluctuations. The goal of this research is to study the characteristics of plasma confinement by means of investigating MHD instabilities of energetic particles and long-range correlation of fluctuations by combining the reflectometer with other measurement methods.

# 2. Principle of Reflectometer

Microwaves produced by an oscillator are injected to plasma and reflected at an electron density corresponding to the cutoff frequency [1, 2]. When electron density fluctuations arise, the position of cutoff layer also changes with the fluctuations. The received waves with the fluctuations are mixed with the reference waves, and then the fluctuations are extracted by a phase detector. We measure electron density fluctuations at various cutoff layers by changing frequency of microwaves. For the measurement system reported here, we use the O-mode of which the cutoff frequency depends only on electron density.

# **3. System Configuration**

We have designed and assembled a microwave reflectometer as shown in Figure 1 and performed a

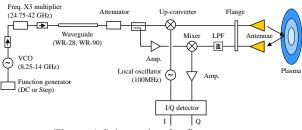


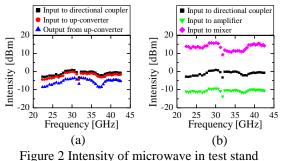
Figure 1 Schematic of reflectometer

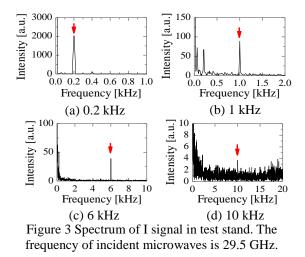
characteristic test. The injection frequency of microwaves to plasma ranges from 24.75 to 42 GHz (Ka-band), corresponding to the O-mode cut-off density from 0.8 to  $2.2 \times 10^{19}$  m<sup>-3</sup>.

A function generator supplies DC or step function to a voltage controlled oscillator (VCO). The frequency band of 24.75-42 GHz is generated by the VCO and a x3 frequency multiplier. The oversized waveguides of WR-90 are used for transmission of 5.8 m long in order to suppress transmission loss. The microwaves are then divided into the waves injected to plasma and the reference waves by using a directional coupler. After the injection waves are up-converted with a signal of 100 MHz generated by a local oscillator, they are injected into the Heliotron J plasma through a pyramidal horn. Two antennae are used as one for injecting waves and the other for receiving waves, located inside the vacuum vessel to remove parasitic reflection. At the receiver section, a low-pass filter is assembled to remove noise coming from a high-power 70 GHz gyrotron. The received microwaves are mixed with the other waves divided by the directional coupler to down-convert to the frequency of 100 MHz with fluctuations, delivering to an I/Q detector. We can estimate the complex phase difference between the received waves and the reference waves through the I and Q signals. The sampling frequency of a data acquisition system is 1 MHz.

#### 4. Characteristic Test

We have examined the performance of the reflectometer in a test stand by using a vibrating reflector to simulate plasma fluctuations. Figure 2 shows the intensity of microwaves in the test stand.





The intensity of microwaves at each point is adjusted by an attenuator located before the directional coupler so that the input signal to the mixer is less than 15 dBm to avoid the damage. The average signal intensity and the flatness after the up-converter are -5.6 dBm and 5.2 dB, respectively.

Figure 3 shows the FFT result of the I signal of I/O detector. It is found that a peak appears at the frequency of the vibrating reflector, indicating that the simulating fluctuations are measured as designed. The maximum measurable frequency of the fluctuations is 10 kHz in the test stand. The amplitude of fluctuations at the frequency higher than 10 kHz from the vibrating reflector may be too low to be measured. It is expected that this system can measure fluctuations of higher frequency because the I/Q detector can measure up to 1 MHz signals as the specifications. In fact, we confirmed in last experimental campaign that fluctuations of 200 kHz could be measured in Heliotron J plasma with a Q-band reflectometer with the same I/Q detector. We will start the density fluctuation measurement using the new Ka-band reflectometer in ongoing experimental campaign.

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